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Form PTO-1449 (REV. 8-83)	-	US Dept. of Commerc PATENT & TRADEMARK OFFIC		ATTY DOCKET NO. 122364			APPLICATION NO. 10/520,461				
INFORMATION DISCLOSURE STATEMENT											
(Use several sheets if necessary)			APPLICANTS Takahiro KISHIOKA et al.								
				FILING DATE			GROUP				
				January 7, 2005		GROOT					
U.S. PATENT DOCUMENTS											
EXAMINER INITIAL		DOCUMENT NUMBER		DATE	NAME			CLASS	SUB CLASS		
ACW	1	US 5,919,599	7/6/1999		MEADOR et al.						
ACW	2	US 5,693,691	12/	2/1997	FLAIM et al.				-		
ACW	3	US 6,083,665	7/4	/2000	SATO et al.						
ACI	4	US 6,090,531	7/1	8/2000	MIZUTANI et al.	ΓΑΝΙ et al.					
ACW	5	US 6,544,717 B2	4/8	/2003	HIROSAKI et al.						
ACW	6	US 6,284,428 B1	9/4	/2001	HIROSAKI et al.						
ACW	7	US 2001/0049072 A1	12/	2/6/2001 HIROSAKI et al.							
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		DOCUMENT NUMBER		DATE	COUNTRY			CLASS	SUB CLASS		
ACW	8	JP A 2000-221689 w/ ab & trl	8/11/2001		JAPAN						
ACW	9	JP A 2000-284491 w/ ab & trl	10/13/2000		JAPAN						
ACW	10	JP A 2002-148791 w/ ab & trl	5/22/2002		JAPAN						
ACW	11	JP A 2000-221690 w/ ab & trl	8/11/2000		JAPAN						
ACW	12	JP A 2001-5186 w/ ab & trl	1/1:	2/2001	JAPAN			•			
ACW	13	JP A 11-84673 w/ ab & trl	3/2	26/1999 JAPAN							
ACW	14	JP A 2000-010293 w/ ab & trl	1/1-	4/2000	JAPAN	•					
ACW	15	JP A 10-333336 w/ ab & trl	12/	18/1998	JAPAN .						
ACW	16	WO 02/069046 A1	2/2	0/2002	WIPO						
		OTHER DOCUMENTS (Inc	cludir	ng Author,	Title, Date, Pertinent Pages, et	c.)					
ACW	17	LYNCH et al., "Properties and Performance of Near UV Reflectivity Control Layers," <i>Proceedings of SPIE</i> , vol. 2195, pp. 225-229 {1994}									
ACW	18	TAYLOR et al., "Methacrylate Resists and Antireflective Coatings for 193 nm Lithography," Proceedings of SPIE," vol. 3678, pp. 174-185 (March 1999)									
ACW	19	MEADOR et al., "Recent Progress in 193 nm Antireflective Coatings," <i>Proceedings of SPIE</i> , vol. 3678, pp. 800-809 {March 1999}									
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EXAMINER /Amanda C. Walke/ DATE CONSIDERED 09/0					5/2006						
Examiner: Initial if citation considered, whether or not citation is in conformance with M.P.E.P. 609; draw line through citation if not in conformance and not considered. Include copy of this form with next communication to applicant.											

Date: April 20, 2005